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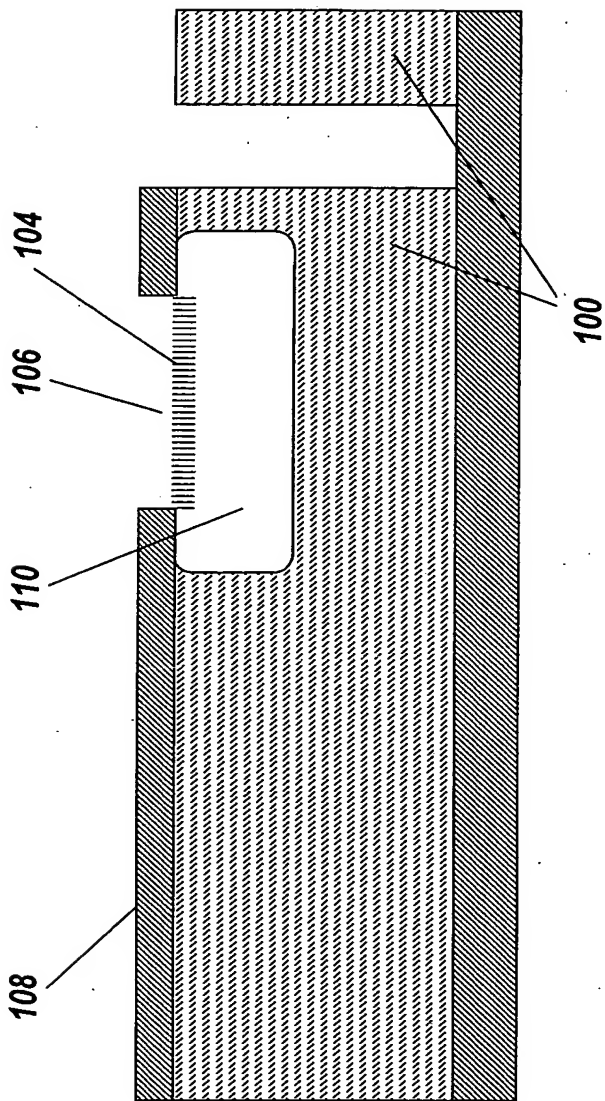


Fig. 1



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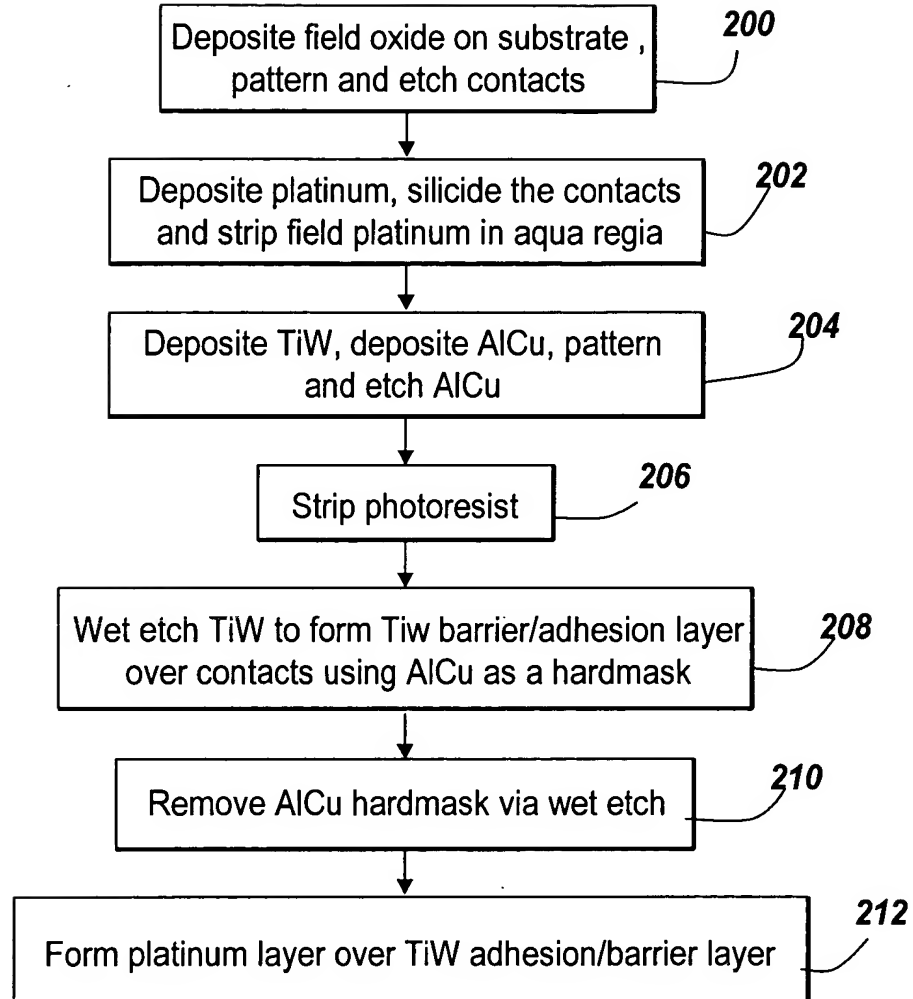


Fig. 2

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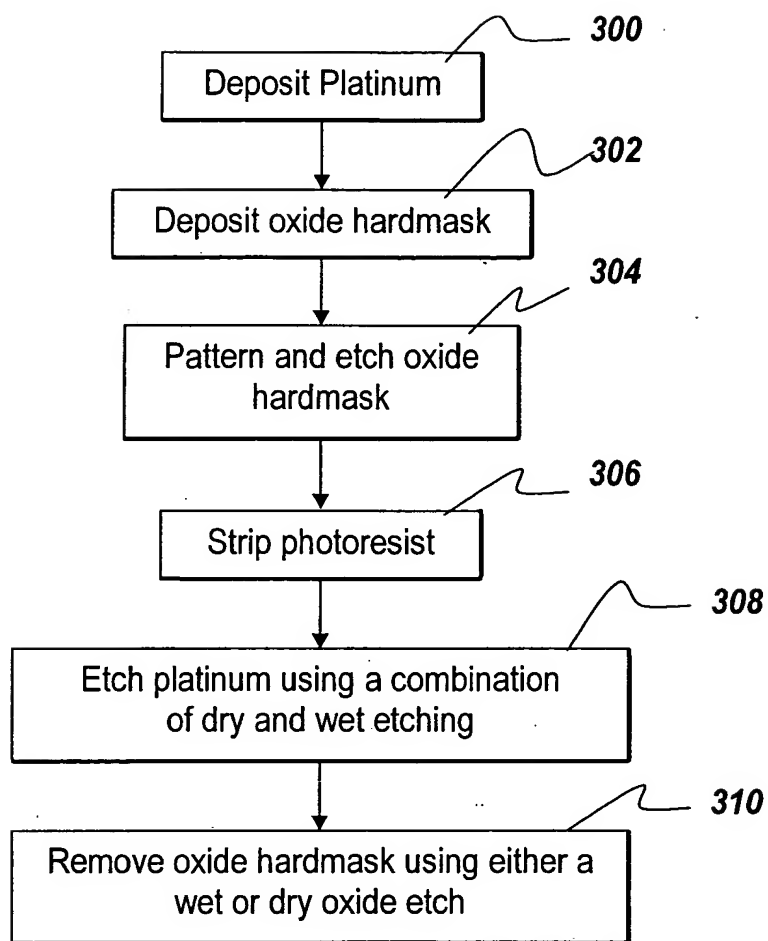


Fig. 3

Pattern and etch contacts

Strip resist

Deposit Platinum and silicide the contacts

Strip field Pt in aqua regia

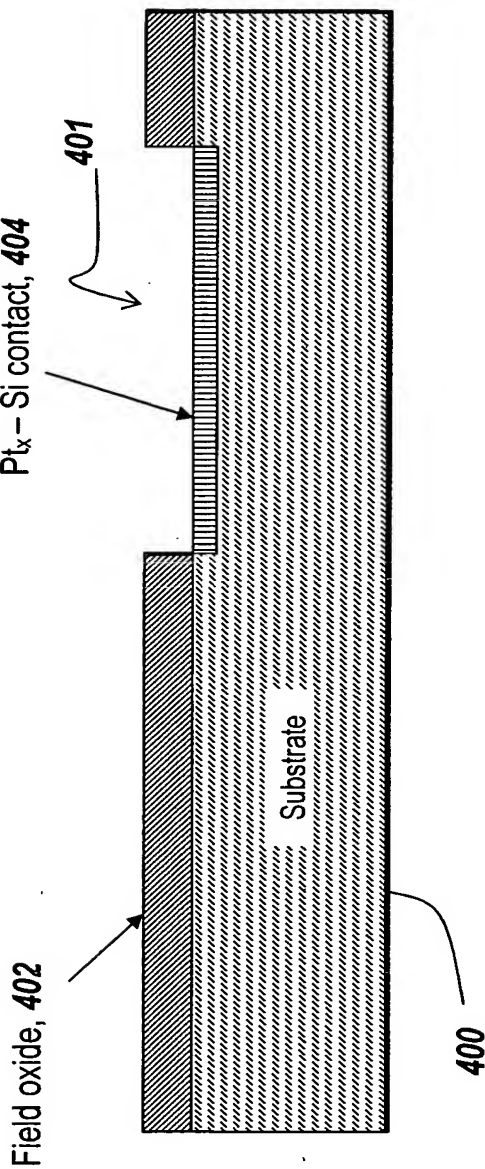


Fig. 4a

Deposit TiW
Pattern and etch TiW barrier over contacts
Strip resist

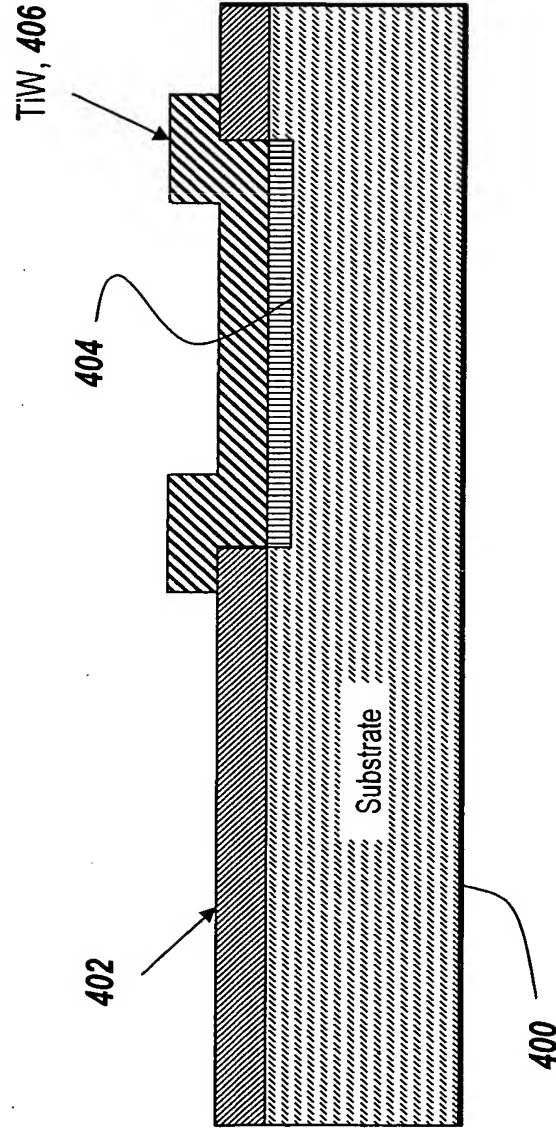


Fig. 4b

Deposit Platinum for interconnect
 Deposit oxide for hardmask
 Pattern and etch hardmask
 Strip resist

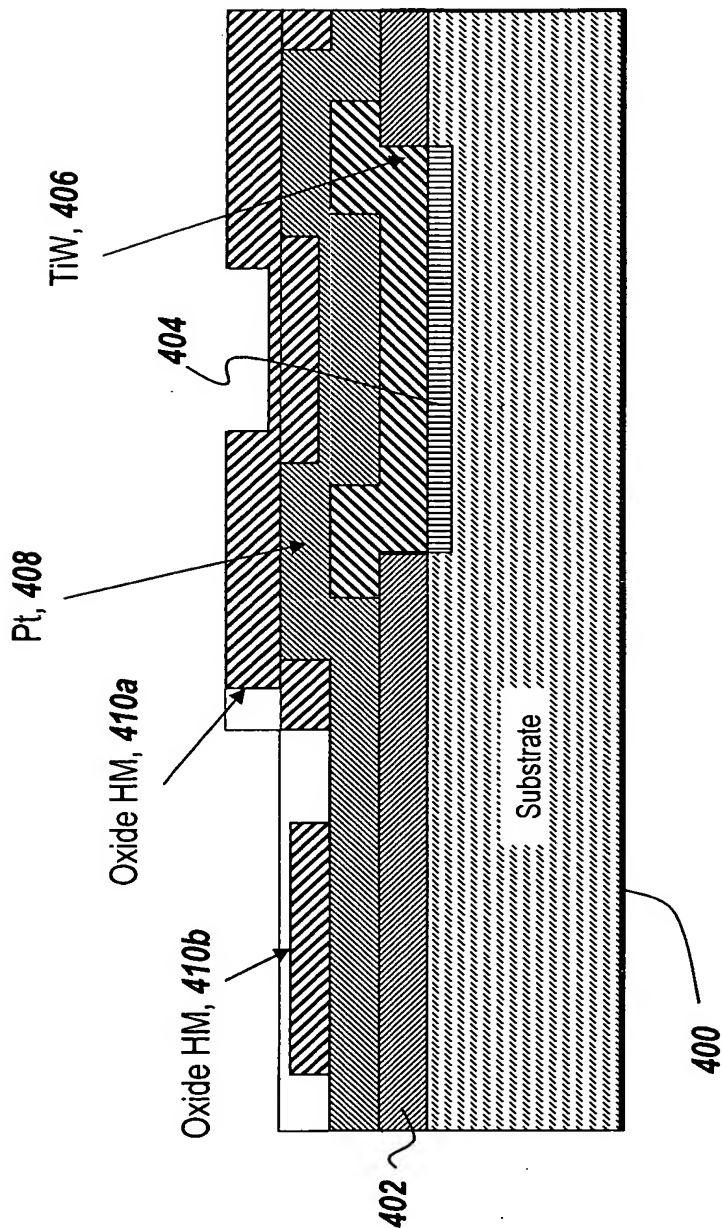


Fig. 4c

Etch Platinum for interconnect

Remove hardmask

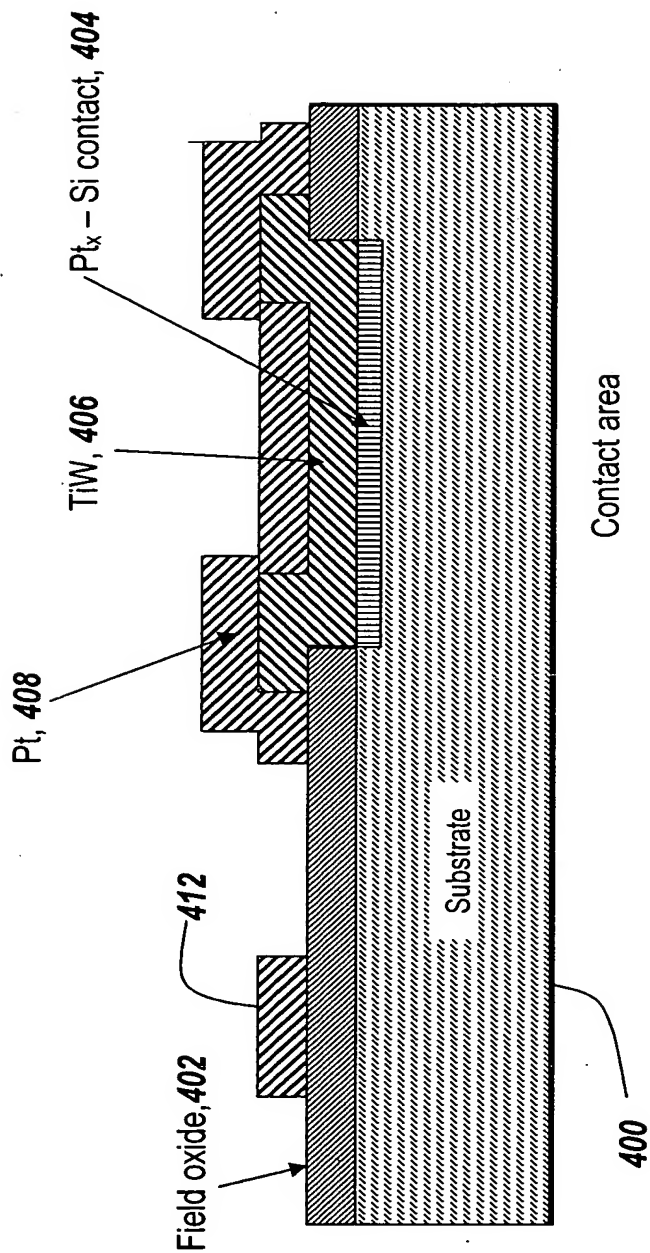


Fig. 4d

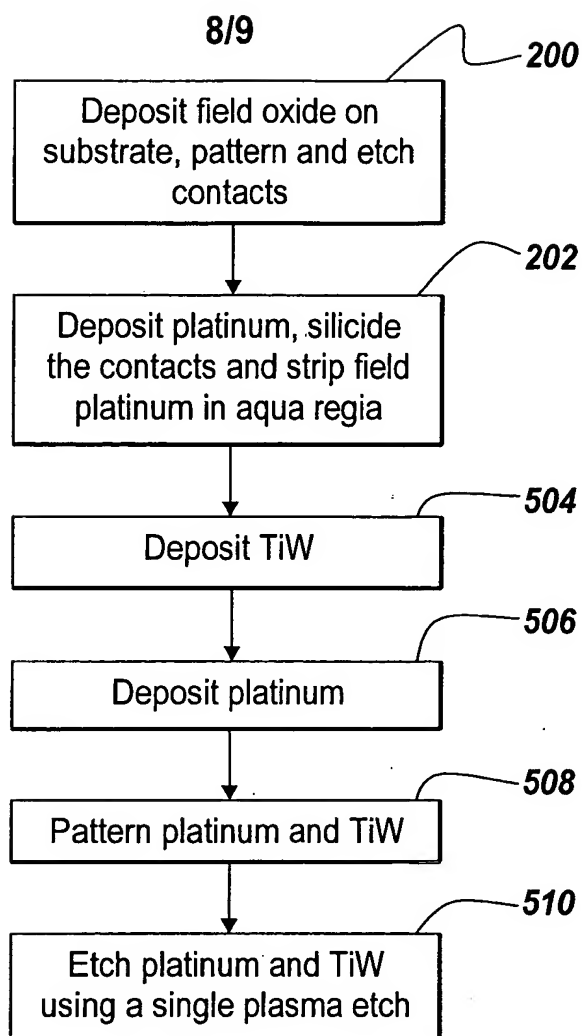


Fig. 5

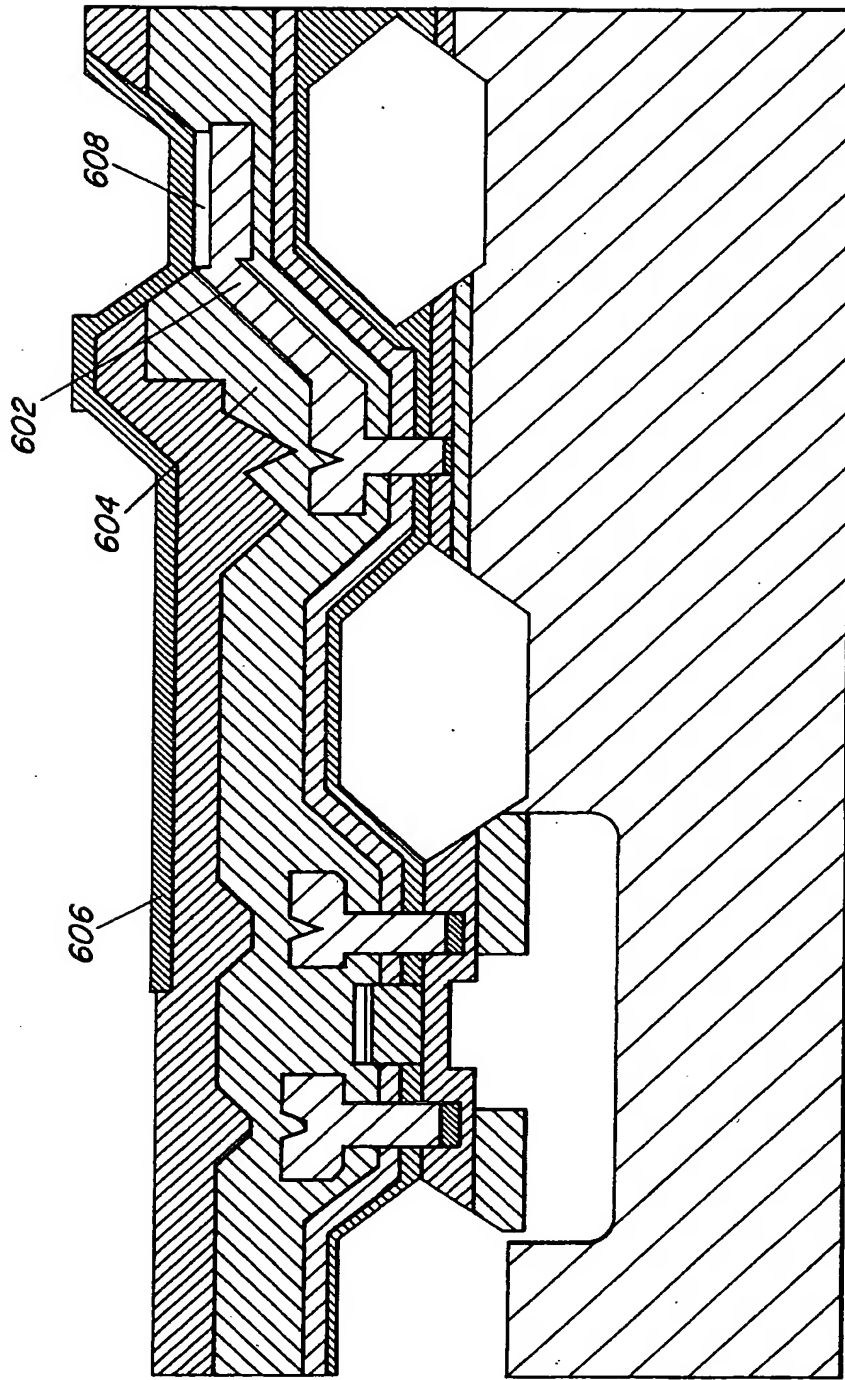


Fig. 6